

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Hideki Fujiwara

Application No.: 10/599,440

Confirmation No.: 8901

Filed: September 28, 2006

Art Unit: 1716

For: SILICON ELECTRODE PLATE FOR PLASMA  
ETCHING WITH SUPERIOR DURABILITY

Examiner: Anna M Crowell

**TRANSMITTAL OF POWER OF ATTORNEY AND STATEMENT UNDER 37 CFR §3.73(b)**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Submitted herewith is a Power of Attorney from the Assignee.

In compliance with 37 CFR §3.73(b), the undersigned hereby states that he is authorized to act on behalf of the assignees of the entire right, title and interest in the patent application identified above by virtue of an assignment from the inventor of the patent application identified above.

The assignment to SUMCO CORPORATION and MITSUBISHI MATERIALS CORPORATION was recorded in the United States Patent and Trademark Office at Reel 018346, Frame 0660, or for which a copy thereof is attached.

In accordance with 37 CFR §3.36(a), submission of this Power of Attorney revokes any powers of attorney previously given.

All Correspondence in connection with this application should be sent to Leason Ellis LLP, customer no. 76808, telephone no. 914-288-0022.

Dated: October 26, 2010

Respectfully submitted,

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